

Opportunity Title: Thin Film Materials and Optical Coatings for Advanced Ultraviolet Instrumentation

Opportunity Reference Code: 0223-NPP-MAR26-JPL-TechDev

Organization National Aeronautics and Space Administration (NASA)

Reference Code 0223-NPP-MAR26-JPL-TechDev

How to Apply All applications must be submitted in [Zintellect](#)

Please visit the NASA Postdoctoral Program website for application instructions and requirements: [How to Apply | NASA Postdoctoral Program \(orau.org\)](#).

A complete application to the NASA Postdoctoral Program includes:

1. Research proposal
2. Three letters of recommendation
3. Official doctoral transcript documents

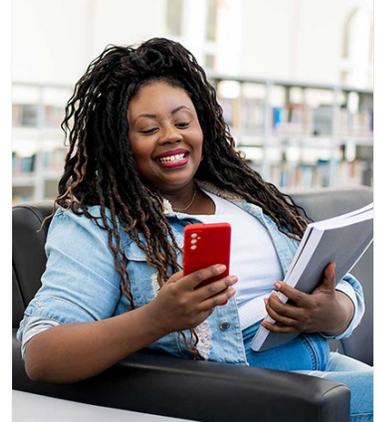
Application Deadline 4/2/2026 6:00:59 PM Eastern Time Zone

Description About the [NASA Postdoctoral Program](#)

The [NASA Postdoctoral Program \(NPP\)](#) offers unique research opportunities to highly-talented scientists to engage in ongoing NASA research projects at a NASA Center, NASA Headquarters, or at a NASA-affiliated research institute. These one- to three-year fellowships are competitive and are designed to advance NASA's missions in space science, Earth science, aeronautics, space operations, exploration systems, and astrobiology.

Description:

Ultraviolet remote sensing instrumentation requires a wide variety of optical coatings in the design of a complete optical system, ranging from broadband reflective mirror coatings, to many-multilayer, all-dielectric structures for components like dichroic beamsplitters and narrowband filter coatings. Specialty UV coatings operating at wavelengths shorter than 200 nm are not widely available from commercial suppliers and generally require the use of humidity-sensitive materials like LiF, AlF₃, and LaF₃. This project will support ongoing research at JPL in new methods for the fabrication of these thin film coatings focused on the use of atomic layer deposition (ALD) and atomic layer etching (ALE). Such coatings may be deposited on optical components like mirrors and diffraction gratings, or integrated on advanced CCD/CMOS detector systems. Applicants with interest and expertise in thin film coatings and ALD/ALE techniques would support delivery of these components to sub-orbital and orbital space instrumentation and identify new directions for this research. Work would be performed at JPL's Microdevices Laboratory using existing and/or newly constructed vacuum deposition chambers. Possible activities include the development of new ALD and ALE processes, optical characterization of the resulting thin films, electro-optical characterization of detector systems, hardware modification of custom vacuum chambers, and software modification of control systems to support both deposition and



Whether you are just starting your career or already at a senior level, ORAU offers internships, fellowships, research opportunities, and contract positions that can provide you with invaluable experience. Download the ORAU Pathfinder mobile app and find the right opportunity to propel you along your career path!

Visit ORAU Pathfinder [↗](#)



Opportunity Title: Thin Film Materials and Optical Coatings for Advanced Ultraviolet Instrumentation

Opportunity Reference Code: 0223-NPP-MAR26-JPL-TechDev

characterization.

Location:

Jet Propulsion Laboratory
Pasadena, California

Field of Science:Technology Development

Advisors:

John Joseph Hennessy
john.j.hennessy@jpl.nasa.gov
(818) 354-4808

Applications with citizens from Designated Countries will not be accepted at this time, unless they are Legal Permanent Residents of the United States. A complete list of Designated Countries can be found at: <https://www.nasa.gov/oiir/export-control>.

Eligibility is currently open to:

- U.S. Citizens;
- U.S. Lawful Permanent Residents (LPR);
- Foreign Nationals eligible for an Exchange Visitor J-1 visa status; and,
- Applicants for LPR, asylees, or refugees in the U.S. at the time of application with 1) a valid EAD card and 2) I-485 or I-589 forms in pending status

Questions about this opportunity? Please email npp@orau.org

Point of Contact [Mikeala](#)

Eligibility Requirements • **Degree:** Doctoral Degree.